

Electronic Acknowledgement Receipt

EFS ID:	1460693
Application Number:	10530562
International Application Number:	
Confirmation Number:	8996
Title of Invention:	Production method for thin-film crystal wafer, semiconductor device using it and production method therefor
First Named Inventor/Applicant Name:	Masahiko Hata
Customer Number:	23373
Filer:	John Timothy Callahan/Elaine Barton
Filer Authorized By:	John Timothy Callahan
Attorney Docket Number:	Q87267
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File Listing:

Document Number	Document Description	File Name	File Size(Bytes)	Multi Part /.zip	Pages (if appl.)
1	NPL Documents	Q87267reference.pdf	528199	no	9

Warnings:

Information:	
Total Files Size (in bytes):	528199
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